## TITLE: METHOD FOR FORMING SACRIFICIAL OXIDE LAYER Inventor: Shu-Ya HSU Docket No. 4425-177

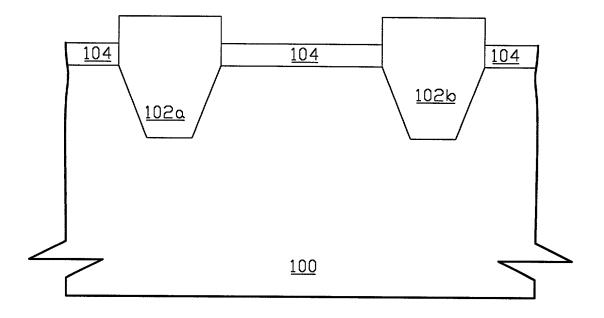


FIG.1(Prior Art)

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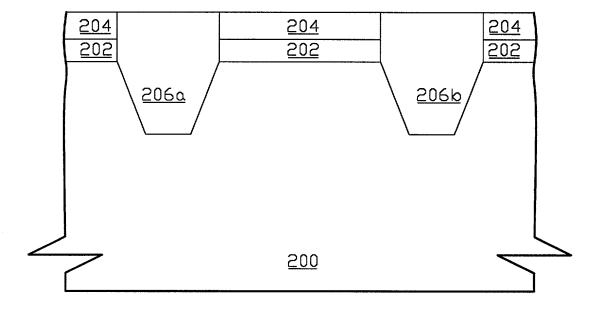


FIG.2A

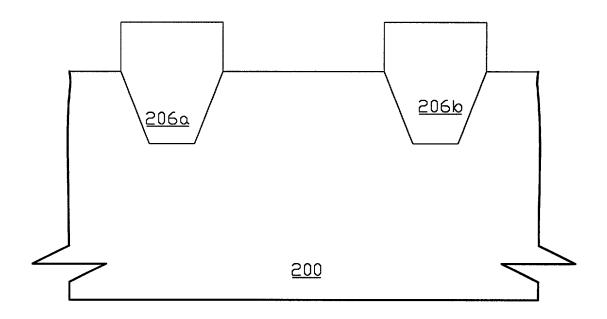


FIG.2B

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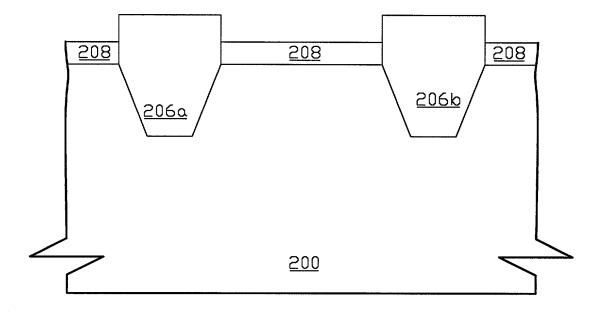


FIG.2C

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